

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| In re Patent Application of: |) | |
| Hidekazu MIYAIRI et al. |) | Group Art Unit: 2828 |
| Application No. 10/658,472 |) | Examiner: Phillip Nguyen |
| Filed: September 10, 2003 |) | Confirmation No. 4070 |
| For: LASER APPARATUS, LASER IRRADIATION METHOD, AND MANUFACTURING METHOD OF SEMICONDUCTOR DEVICE |) | Date: May 29, 2007 |

AMENDMENT

Mail Stop RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed February 26, 2007, please amend the above identified application as follows.